

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 217470US6PCT		SERIAL NO. 10/030,272	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Olivier RAYSSAC, et al.			
				FILING DATE January 8, 2002		GROUP 1755	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
MAO	AA	5,029,418	07/09/91	D. N. BULL			
MAO	AB	3,918,150	11/11/75	F. C. GANTLEY			
MAO	AC	5,863,375	01/28/99	G-H. CHA, et al			
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
MAO	AO	0 925 888	06/30/99	EUROPE			
MAO	AP	62-230537	10/09/87	JAPAN (submitting English Abstract only)			
MAO	AQ	2 752 332	02/13/98	FRANCE (with English Abstract)			X
MAO	AR	WO 98/52216	11/19/98	WIPO			
MAO	AS	0 703 609	03/27/96	EUROPE (with English Abstract)			X
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
MAO	AW	W. P. MASZARA, et al., J. Appl. Phys., Vol. 64, No. 10, pps. 4943-4950, "BONDING OF SILICON WAFERS FOR SILICON-ON-INSULATOR", November 15, 1988					
MAO	AX	C. MALEVILLE, et al., Electrochemical Society Proceedings, Vol. 97-36, pps. 46-55					
MAO	AY	O. RAYSSAC, et al., 2 nd International Conference on Materials for Micro-Electronics, pps. 183-191, "INFLUENCE OF SURFACE CHARACTERISTICS ON DIRECT WAFER BONDING", September 14/15, 1998					
	AZ						
Examiner Mark A. Osale					Date Considered 5-29-03		

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.